



Instrumentation

June 10, 1998

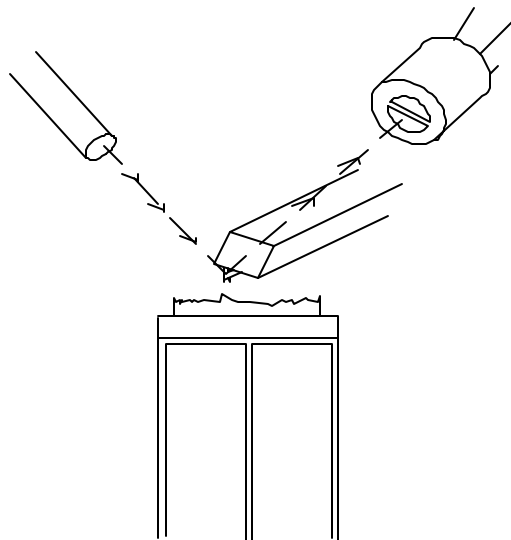
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Optical beam deflection detection Method

● Force Sensing method

- ✧ tunneling detection
- ✧ capacitance detection method
- ✧ interferometry method
 - ✓ somewhat complicated
- ✧ optical beam deflection detection method
 - ✓ most commonly used method
 - ✓ laser diode($\lambda=670\text{nm}$)
 - ✓ bicell photodiode



● detection mechanism

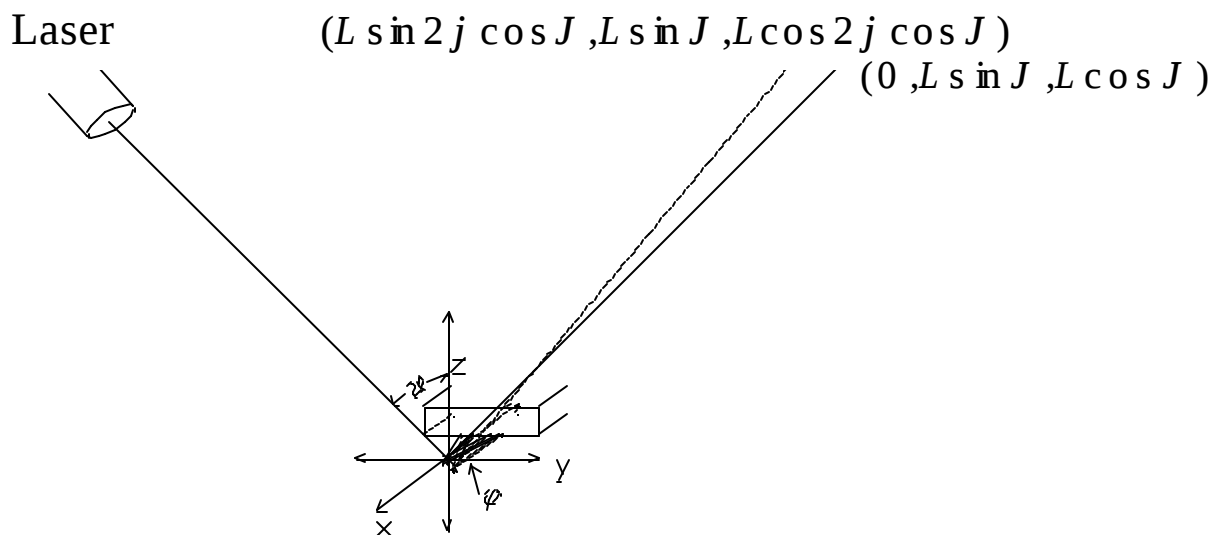
L : distance between PSD and cantilever

ϑ : incident angle with z axis in the yz plane

φ : the deflection angle of cantilever by F_{ext}

δz : change of z coordinate of cantilever by F_{ext}

λ : length of cantilever



◇ the change of x , y , z on the detector

$$\Delta x \cong 2L \cos J \left(\frac{dz}{\lambda} \right)$$

$$\Delta y = 0$$

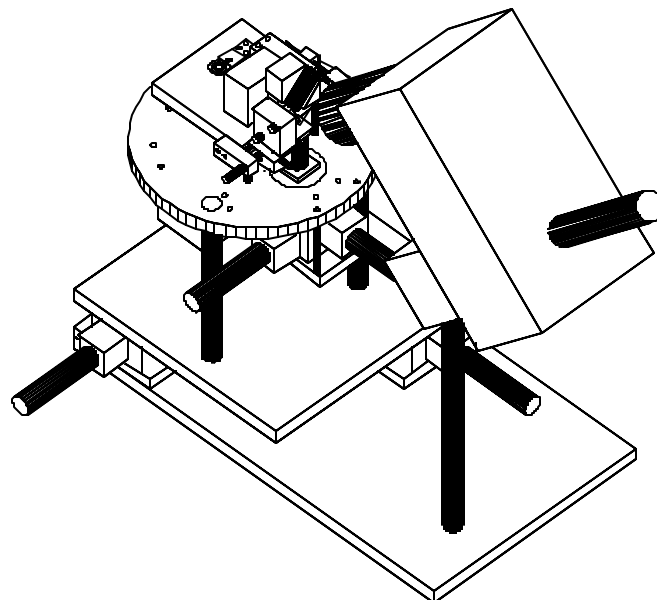
$$\Delta z \cong -2L \cos J \left(\frac{dz}{\lambda} \right)^2$$

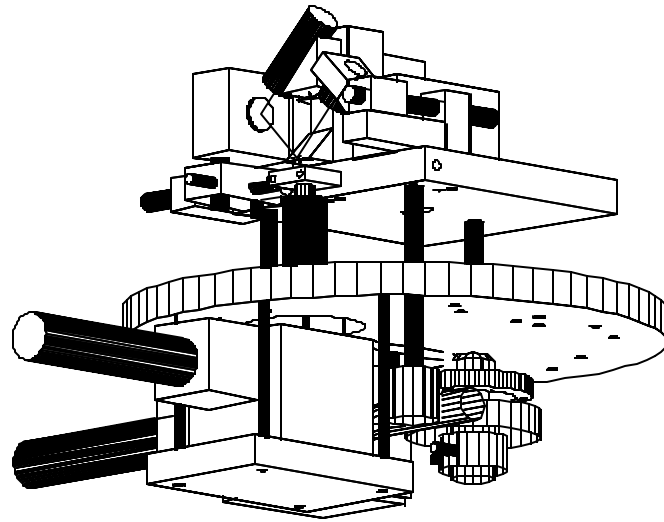
✧ For $L=2\text{cm}$, $J=45^\circ$, $l=200\text{mm}$
 $\Delta x \cong 140dz$

Design of Mechanical Parts

● design consideration

- ✧ rigidity and stability
 - ✓ mechanically stiff and symmetric
- ✧ head
 - ✓ optical beam deflection system
 - ✓ metal box for preamplifier
- ✧ base
 - ✓ scanner with XY-translational stage
 - ✓ tip-sample approaching system
- ✧ optical microscope
 - ✓ long-working-distance objective
 - ✓ CCD camera with video monitor





- tip-sample approaching system

- ✧ coarse approach

- ✓ two thumbscrews

- ✧ fine approach

- ✓ stepping motor(1.8° /pulse)

- ✓ micrometer (0.5mm / turn) with worm gear(1/80)

- ✓ approaching rate: $40\text{\AA}/\text{pulse}$

- scanner

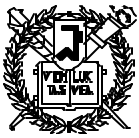
- ✧ piezoelectric tube with sample holder

- ✧ XY-translational stage

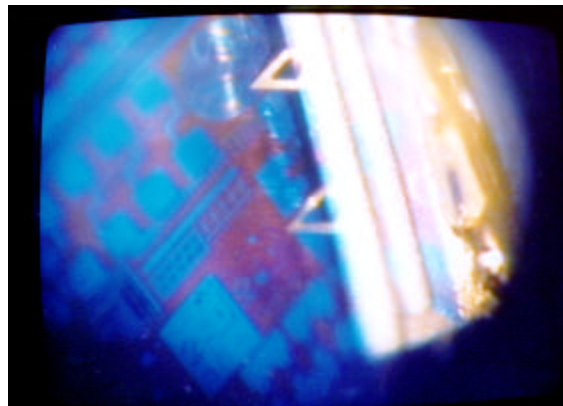
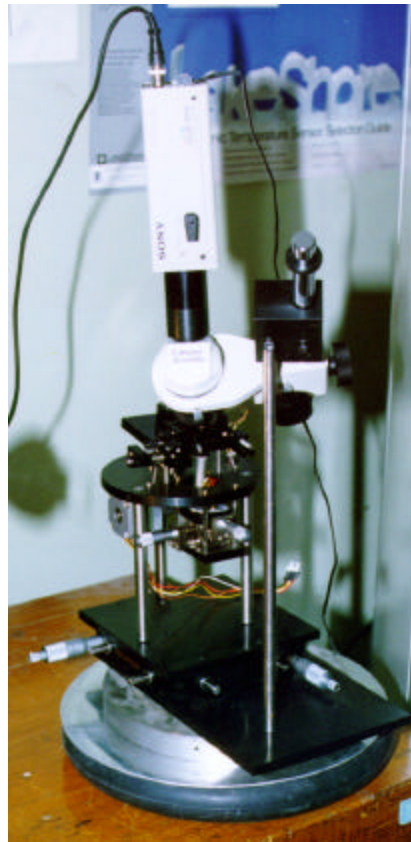
- ✧ maximum scan area: $40\mu\text{m} \times 40\mu\text{m}$

- ✧ calibration

- ✓ Michelson-Moley interferometry



● Scanning Force Microscope



video monitor

● cantilever

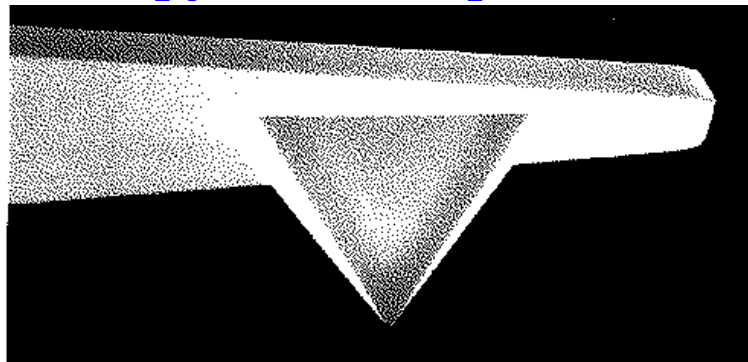
✧ commercial cantilever with 'V' shape



✧ contact mode

✓ Si_3N_4 , $k=0.064\text{N/m}$, $\omega_0=17\text{kHz}$

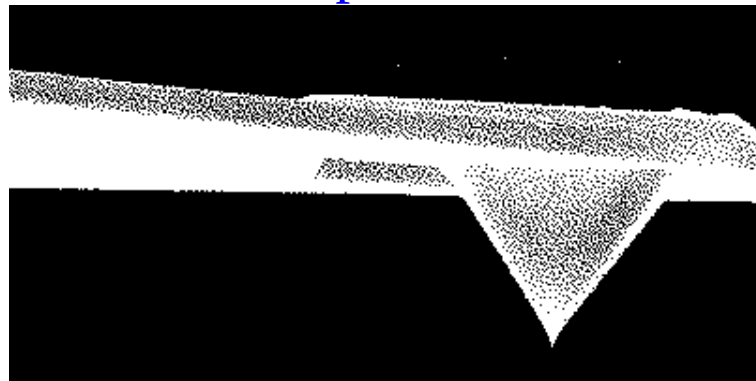
✓ microlever : pyramidal tip



✧ noncontact mode

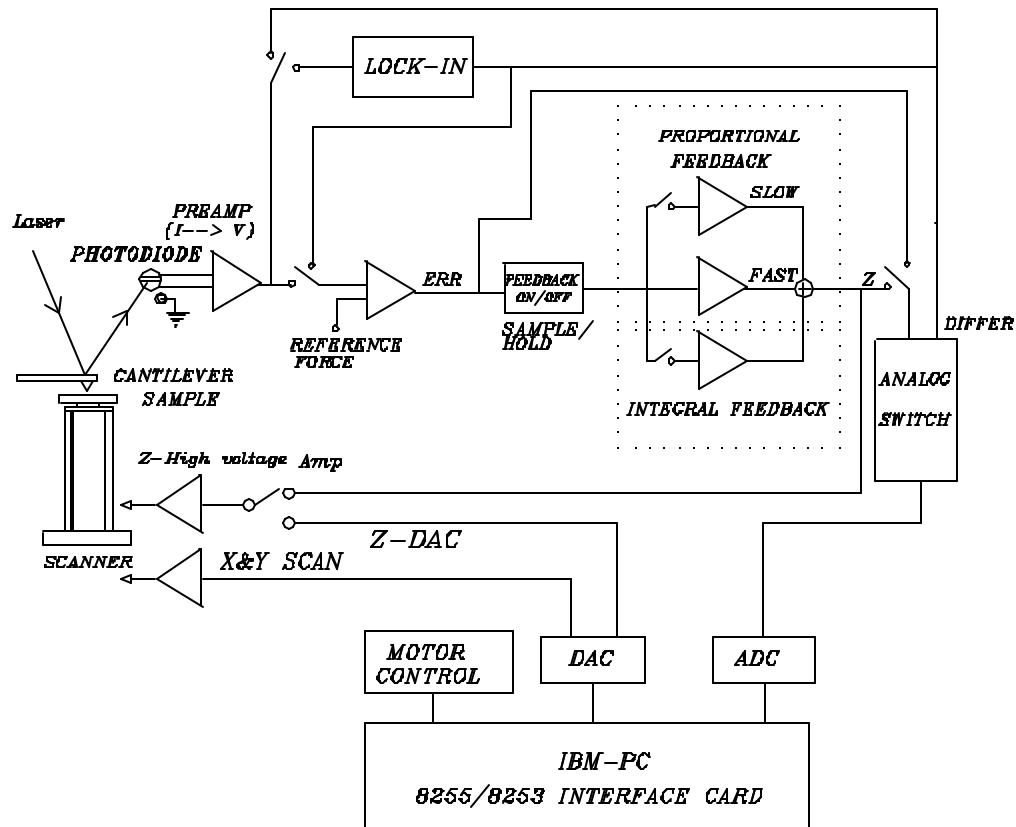
✓ doped Si, $k=2.1\text{N/m}$, $\omega_0=109\text{kHz}$

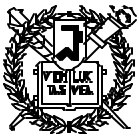
✓ ultralever : conical tip



Electronics Parts

- block diagram of SFM electronics
 - ✓ feedback circuit
 - ✓ scan size controller and PZT driver
 - ✓ stepping motor controller
 - ✓ computer interface
 - ✓ rms-to-dc converter
 - ✓ two lock-in operation

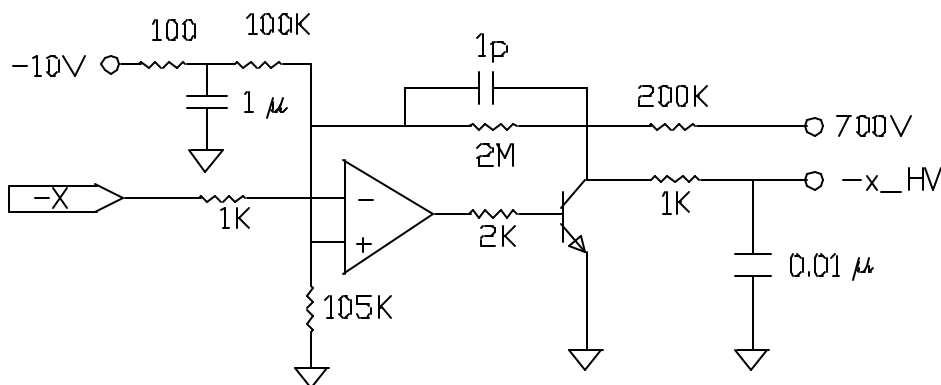
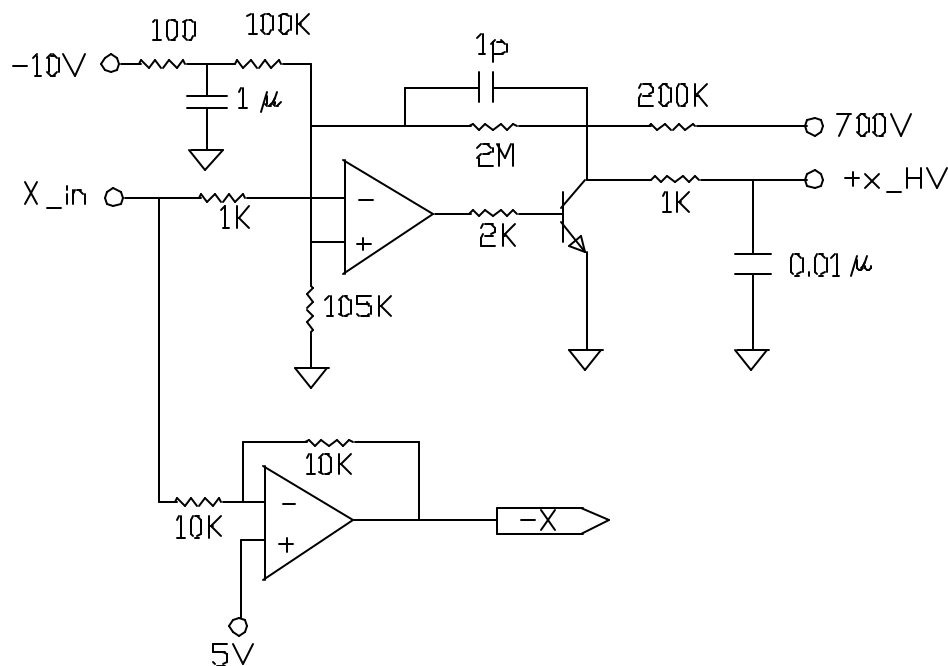


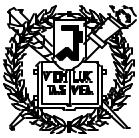


● PZT tube driving circuits

✧ high voltage amp. for X-Y piezo

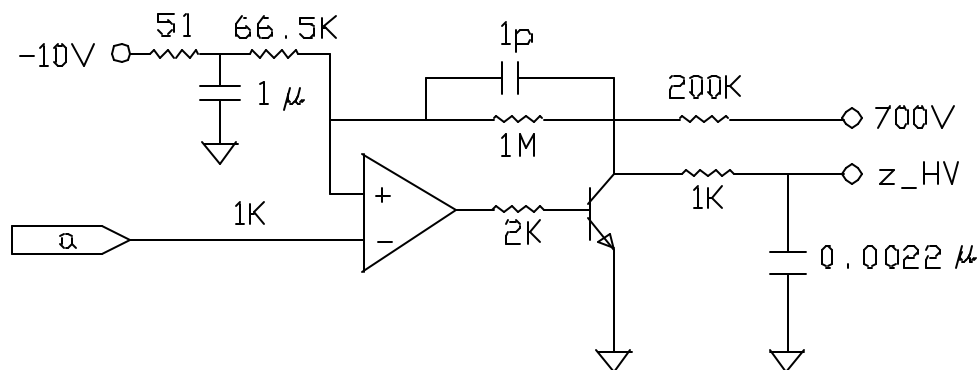
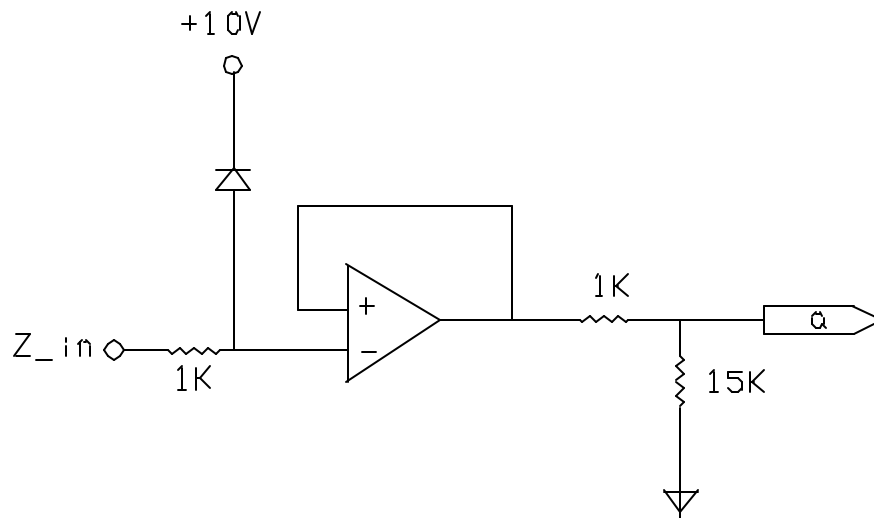
- ✓ X_{in} : inputs from D/A converter via size and offset controller
- ✓ $+x_{HV}$:200V-600V
- ✓ $-x_{HV}$:600V-200V
- ✓ Δx_{HV} :-400V - +400V





✧ high voltage amp. for Z-piezo

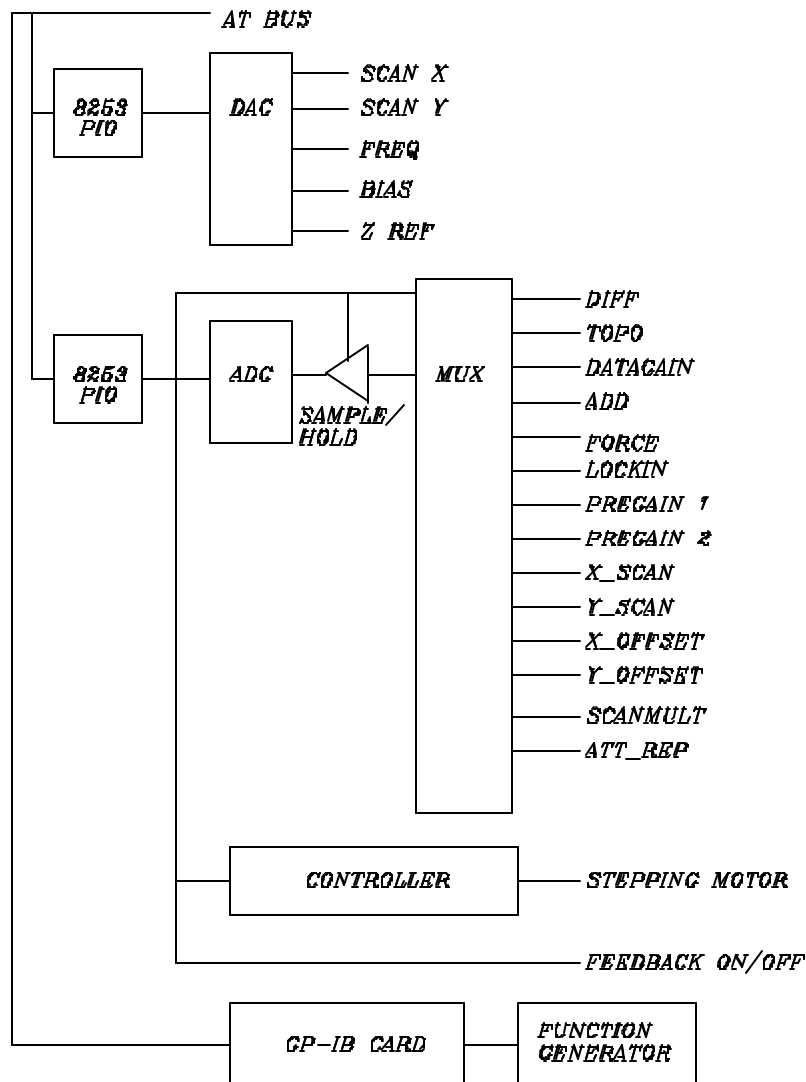
- ✓ Z_{in} : feedback output, output from computer via D/A converter
- ✓ z_{HV} : 0V - 300V





● I/O interface

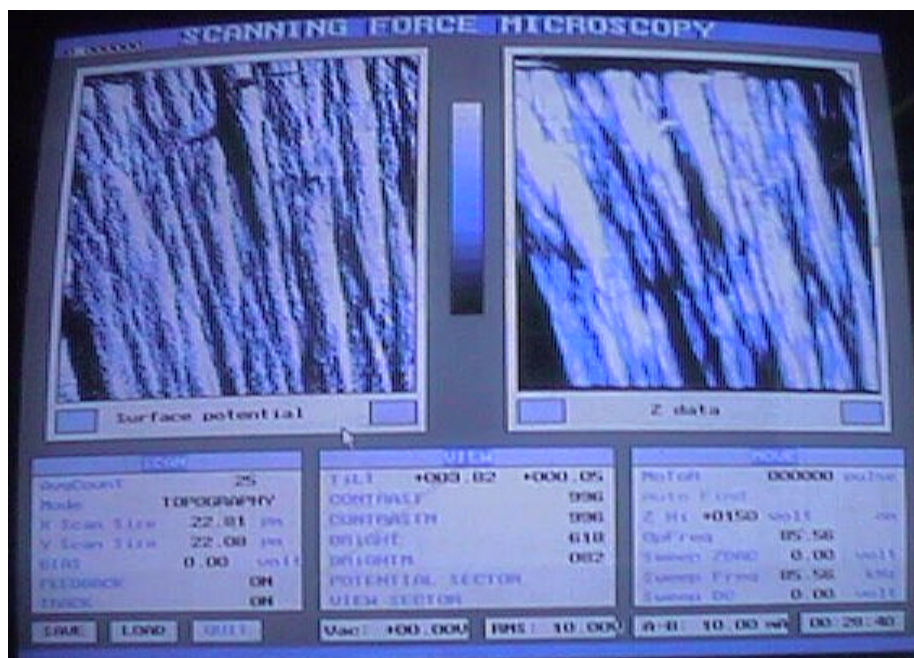
- ✧ 8255 PIO(programmable input/output)
- ✧ A/D converter
- ✧ multiplex(SPC 16s)
 - ✓ A-B, data, set value, scan size, rms *etc.*
- ✧ D/A converter
 - ✓ x scan, y scan, z reference and bias
- ✧ feedback ON/OFF
- ✧ pulse signal for stepping motor



Software

- data acquisition

- ✓ 256×256 pixels
- ✓ simultaneous acquisition of two data
- ✓ sectioning profile
- ✓ monitoring of force and amplitude



● force spectroscopy

- ✧ amplitude-frequency curve
 - ✓ selecting operation frequency
- ✧ force-distance curve
 - ✓ force set in contact mode
- ✧ amplitude-distance curve
 - ✓ selecting operation mode in ac mode
- ✧ amplitude-bias curve
 - ✓ scanning potentiometry application